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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Li et al.

Application No. 09/222,588

Filed: December 28, 1998

For: PERFORATED PLASMA
CONFINEMENT RING IN
PLASMA REACTORS



Atty. Dkt. No. LAM1P098

Examiner: Hassanzadeh, P.

Art Unit: 1763

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner of Patents and Trademarks, Washington, DC 20231 on March 27, 2000.

Signed: 

Sandra Halliwell

AMENDMENT

Box Non-Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action mailed January 6, 2000, please enter the following amendments and remarks.

In the Specification

At page 3, line 1, please delete "reactor".

At page 3, line 3, please delete "semiconductor".

In the Claims

Please amend the claims as set for the below.

- sub
B1
A1
1. (amended) A plasma processing reactor for [semiconductor] processing a substrate comprising:
a chamber;

A